Method for removal of scanning and ion microscope image distortions

By using in electron and ion microscopy an invented and patented method for removal of image distortions caused by scanning disturbances, significantly better image quality is obtained in cases of high magnification images initially showing distortions

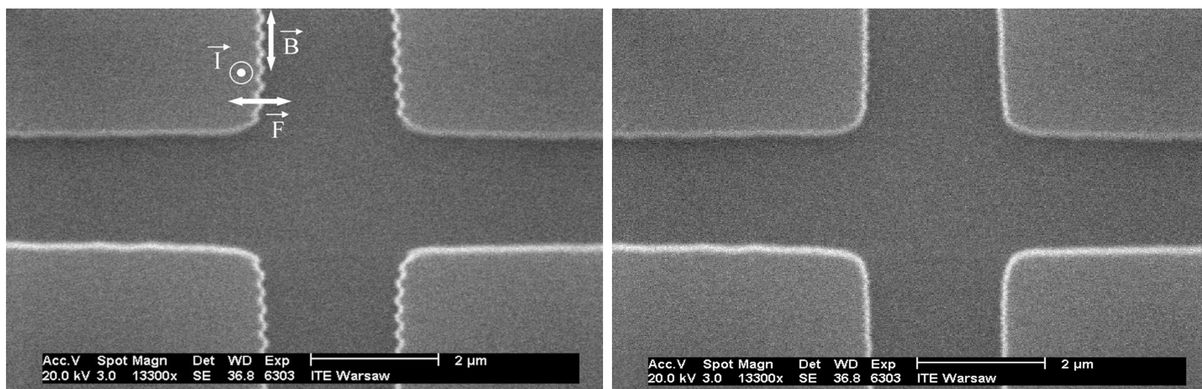

Fig. Shapes of elements imaged by scanning electron microscopy in case of high magnification and scanning disturbances, without (left) and with (right) applying the method. Directions of magnetic field (B) and force (F), disturbing the electron beam (I) are indicated